

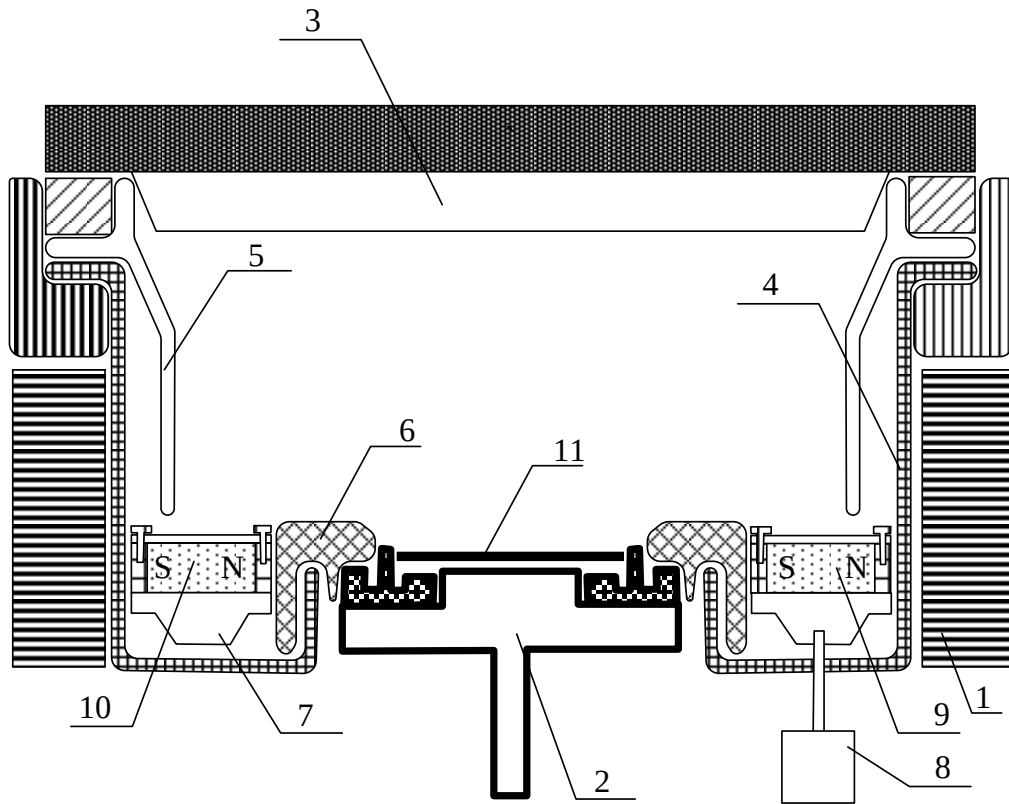


FIG. 1

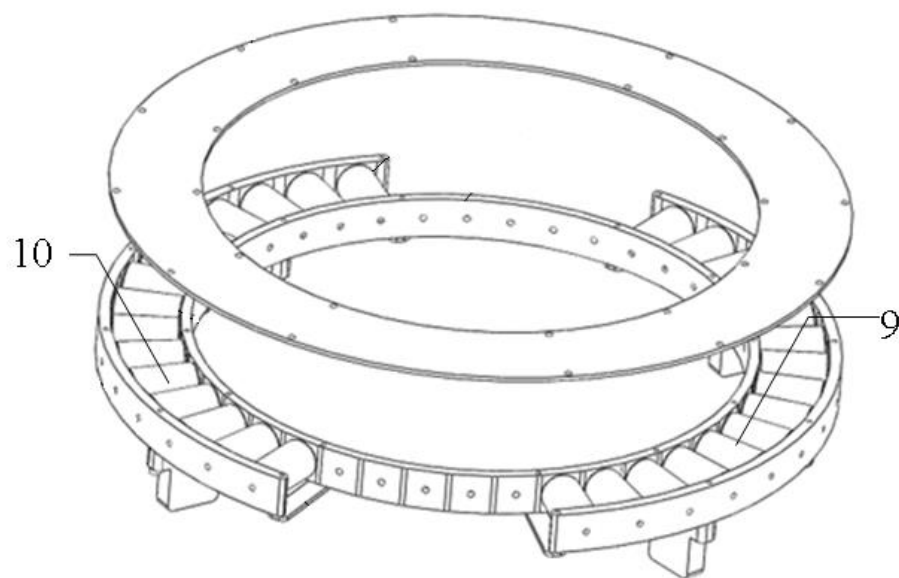


FIG. 2

Rotate a bias magnetic field device by a fixed angle along a circumferential direction of a base very first preset application time length of the target until a total application time length of a target accumulates to an upper limit, each time the bias magnetic field device being rotated in a same direction

S1

FIG. 3

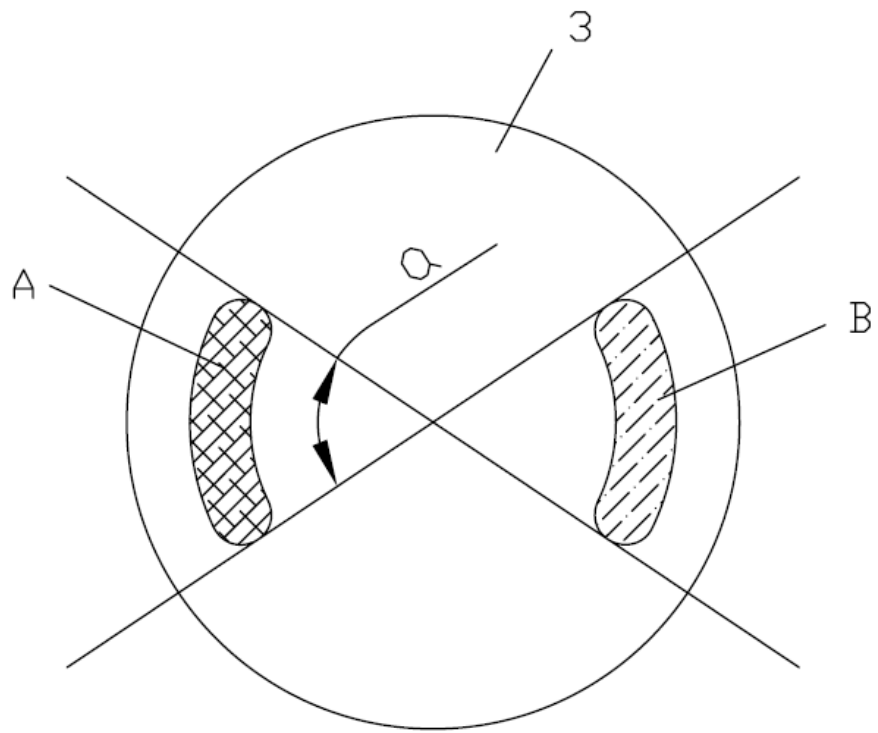


FIG. 4

FIG. 5

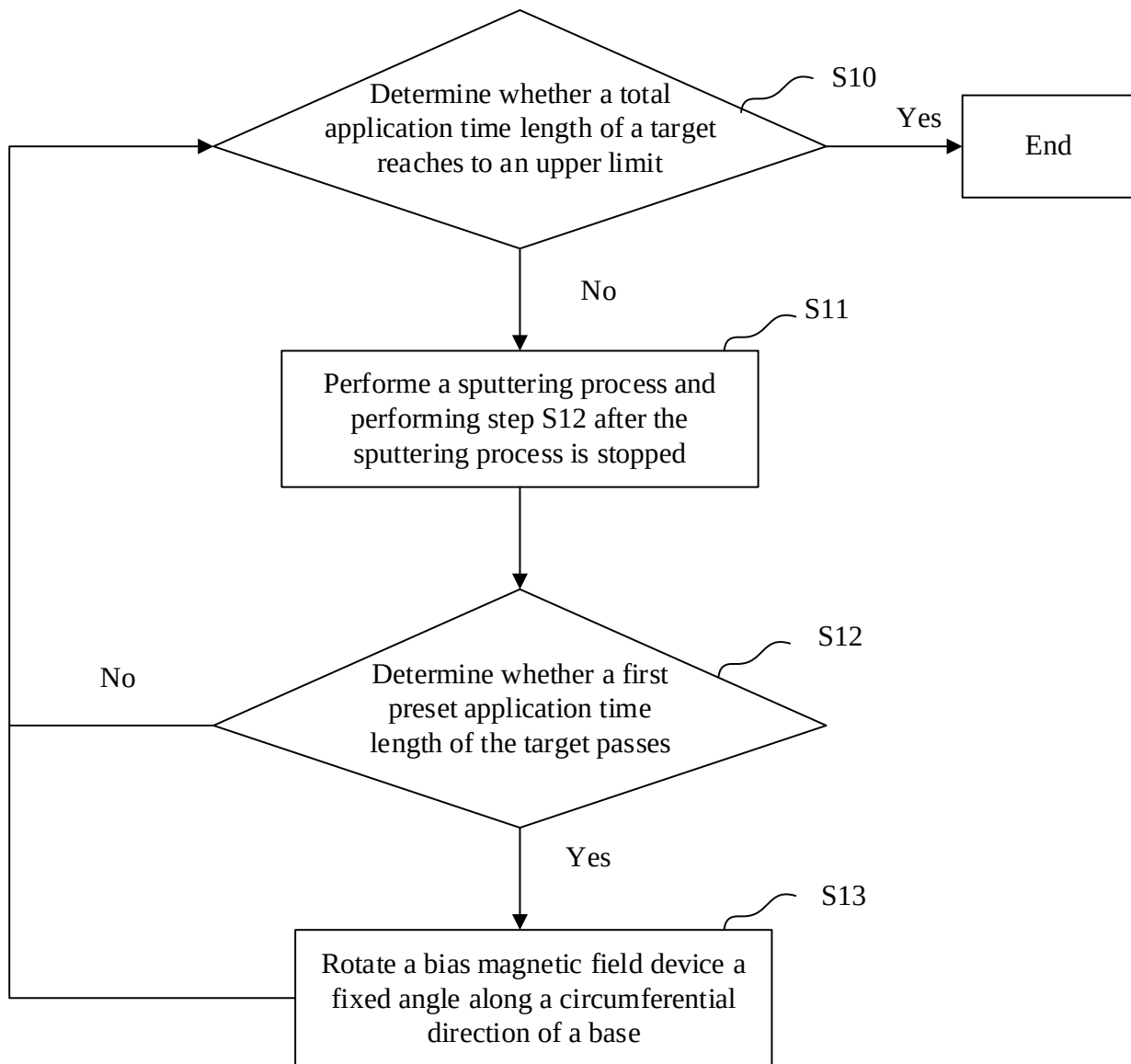


FIG. 6